PATENT APPLICATION

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Attorney Docket No.: 105875

AMENDMENT TRANSMITTAL

In re the Application of

Masaru MITSUI et al.

Group Art Unit: 1752

Application No.: 09/509,472

Examiner:

Y. Clarke

Filed: April 21

April 21, 2000

For:

PHOTOMASK BLANK, PHOTOMASK, METHODS OF MANUFACTURING THE SAME AND

METHOD OF FORMING MICROPATTERN

Director of the U.S. Patent and Trademark Office

Washington, D.C. 20231

Sir:

Transmitted herewith is an Amendment in the above-identified application.

Entitlement to small entity status is hereby asserted.

Small entity status of this application has been established.

The filing fee has been calculated as shown below:

ADD'L C
x 9 \$
x 42 \$

OTHER THAN A
SMALL ENTITY

ΩR	RATE	ADD'L FEE
	x 18	\$108
	x 84	\$
ΩR	+280	\$
		\$108

- (Column 1) (Column 2) (Column 3) **CLAIMS** REMAINING HIGHEST NO. **AFTER PREVIOUSLY PRESENT** AMENDMENT PAID FOR **EXTRA** TOTAL CLAIMS *36 MINUS **30 =6 *5 MINUS **INDEP CLAIMS** =0 \square FIRST PRESENTATION OF MULTIPLE DEP. CLAIM
 - * If the entry in Column 1 is less than the entry in Column 2, write "0" in Column 3.
 - ** If the "Highest Number Previously Paid For" IN THIS SPACE is less than 20, write "20" in this space.
- *** If the "Highest Number Previously Paid For" IN THIS SPACE is less than 3, write "3" in this space.

The "Highest Number Previously Paid For" in this space (Total or Independent) is the highest number found from the equivalent box in Column 1 of a prior Amendment or the number of claims originally filed.

Check No. 137814 in the amount of \$108 is attached. The Director is hereby authorized to charge any other fees that may be required to complete this filing, or to credit any overpayment, to Deposit Account No. 15-0461. Two duplicate copies of this sheet are attached.

DEPOSIT ACCOUNT USE
AUTHORIZATION
Please grant any extension
necessary for entry;
Charge any fee due to our
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Respectfully submitted,

+140

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JAO:JSA:CWB/rxg

Date: January 2, 2003



PATENT APPLICATION

Y. Clarke

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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PRELIMINARY AMENDMENT

Director of the U.S. Patent and Trademark Office Washington, D.C. 20231

Sir:

Prior to further examination of the above-identified application, please amend the application as follows:

IN THE CLAIMS:

Please cancel claims 1-30 without prejudice to or disclaimer of the subject matter contained therein.

Please add new claims 31-66 as follows:

A photomask blank forming a thin film having a shading function and containing one or more transition metals or compounds thereof on a transparent substrate, wherein the thin film restrains a film stress to be small by containing He, and wherein the content of He\in the thin film is in a range of a film stress that the amount of change in flatness degree expressed by the difference in flatness degree between an initial value of the flatness degree which is the flatness degree of the transparent substrate when the

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